

## 2018 EUVL Workshop Keynote Talk

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*Abstract for talk to be published.*

### Presenting Author

Anthony (Tony) Yen is VP and Head of Technology Development Centers Worldwide, ASML. He graduated from Purdue University with a BS degree in electrical engineering and furthered his education at MIT, earning his SM, EE, PhD, and MBA degrees there. As a researcher with Texas Instruments from 1991 to 1997, he worked on various techniques, including early work on optical proximity correction, to enhance the practical resolution of microlithography. From 1997 to 2016, except for a three-year stint at Cymer where he headed its marketing organization, he was with TSMC where he was responsible first for microlithography of TSMC's 0.25, 0.18, 0.15, and 0.13 micron generations of logic integrated circuits and then for building infrastructure of next-generation lithography technologies at SEMATECH, and from 2008 to 2016, for the development of extreme-ultraviolet lithography, including its mask technology, to be used in high-volume manufacturing. He has over 100 US patents and 90 publications, and is a fellow of SPIE and of IEEE.

